

Title (en)
Charging method and charging equipment of diaphragm for condenser microphone

Title (de)
Verfahren zur Ladung und Ladungsgerät einer Membran eines Kondensator-Mikrofon

Title (fr)
Procédé et dispositif de charge pour diaphragme de microphone à condensateur

Publication
EP 1085783 A2 20010321 (EN)

Application
EP 00305827 A 20000710

Priority
KR 19990040432 A 19990920

Abstract (en)
A charging method and equipment of a diaphragm (10) for a condenser microphone capable of charging an electric charge to the diaphragm (back plate) built in the condenser microphone, that is, a thin film made of a high polymer material having a conductive material deposited on the both sides thereof by corona discharging and ion implanting. The method comprises the steps of: supplying positive ions provided from a positive ion generating apparatus (3) and negative ions provided from a negative ion generating apparatus to a path to which a high voltage is applied to thereby form a corresponding space as an air layer of a conductive medium; and implanting electric charges formed by corona discharging upon application of the high voltage to the diaphragm to thereby form electric double layers on the thin film of the high polymer material. <IMAGE>

IPC 1-7
H04R 19/00

IPC 8 full level
H04R 19/01 (2006.01); **H04R 19/00** (2006.01); **H04R 19/04** (2006.01)

CPC (source: EP KR)
H04R 19/00 (2013.01 - KR); **H04R 19/04** (2013.01 - EP)

Cited by
EP1921892A4

Designated contracting state (EPC)
AT BE CH CY DE DK ES FI FR GB GR IE IT LI LU MC NL PT SE

DOCDB simple family (publication)
EP 1085783 A2 20010321; CN 1289219 A 20010328; JP 2001112091 A 20010420; KR 100306262 B1 20011102; KR 20000000129 A 20000115; TW 490986 B 20020611

DOCDB simple family (application)
EP 00305827 A 20000710; CN 00121145 A 20000728; JP 2000209443 A 20000711; KR 19990040432 A 19990920; TW 89114890 A 20000726